

Notice of References Cited	Application/Control No. 10/033,929	Applicant(s)/Patent Under Reexamination ANDO ET AL.	
	Examiner Paul D Kim	Art Unit 3729	Page 1 of 1

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	B	US-4,900,970	02-1990	Ando et al.	310/320
	C	US-4,087,716	05-1978	Heywang, Walter	310/332
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	U	"PZT thin film pressure sensor for on-line monitoring injection molding"; Luo, R.C.; Chien Ming Chen; Industrial Electronics Society, 2000. IECON 2000. 26th Annual Conference of the IEEE , Volume: 4 , 22-28 Oct. 2000; Pages:2394 - 2399.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.